News from the cryostat cleaning & cryogenic infrastructure

Bernhard Schwingenheuer MPI Heidelberg

Motivation & Cleaning method

cryostat ²²²Rn emanation before the copper plate mounting = $13.7 \pm 1.9 \text{ mBq}$

after

 $= 34 \pm 6 \text{ mBq}$

acceptable typically 10 mBq --> need cleaning

Method: 1. spray ball cleaning with acid / alcohol / water

2. CO_{2} cleaning

3. mechanical cleaning with wipes + propanol

after discussions at the last meeting and in Heidelberg --> option 3

after long preparation time cleaning occurred last week & exchange of some small copper pieces

next emanation measurement in preparation

Nameplate installed & stamped by TÜV on 5 Nov 08



Tent with HEPA filter for ventilation above cryostat



Tripod for access

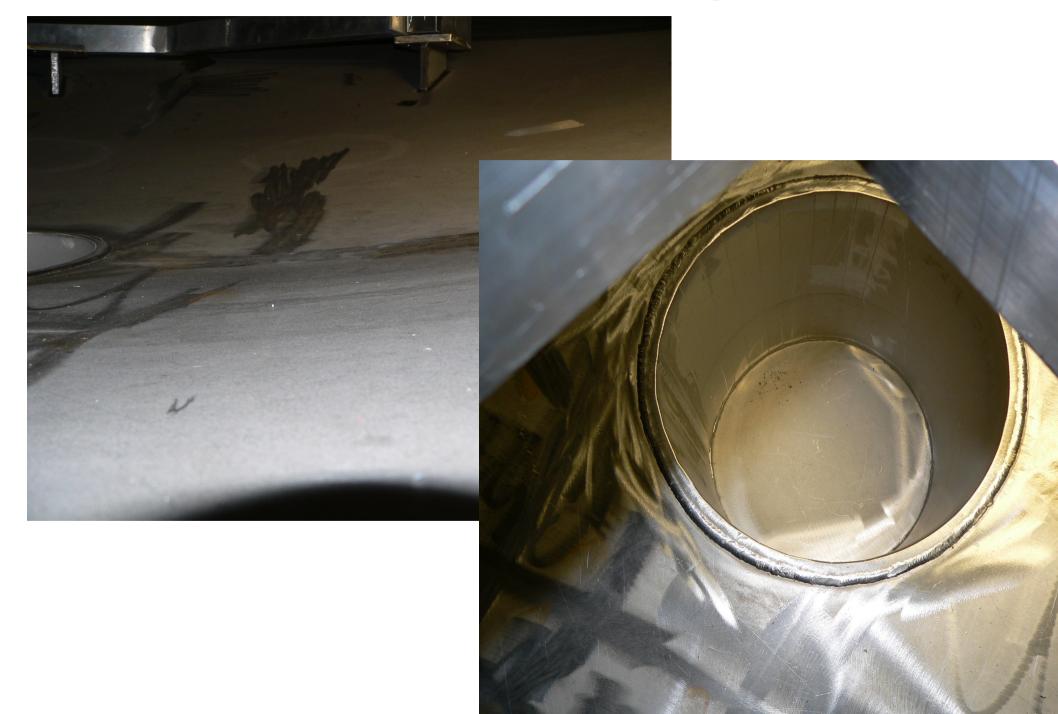






Position of support pads: head is deformed (flattened) by approx 5 mm at these position, check with TÜV if this is a problem

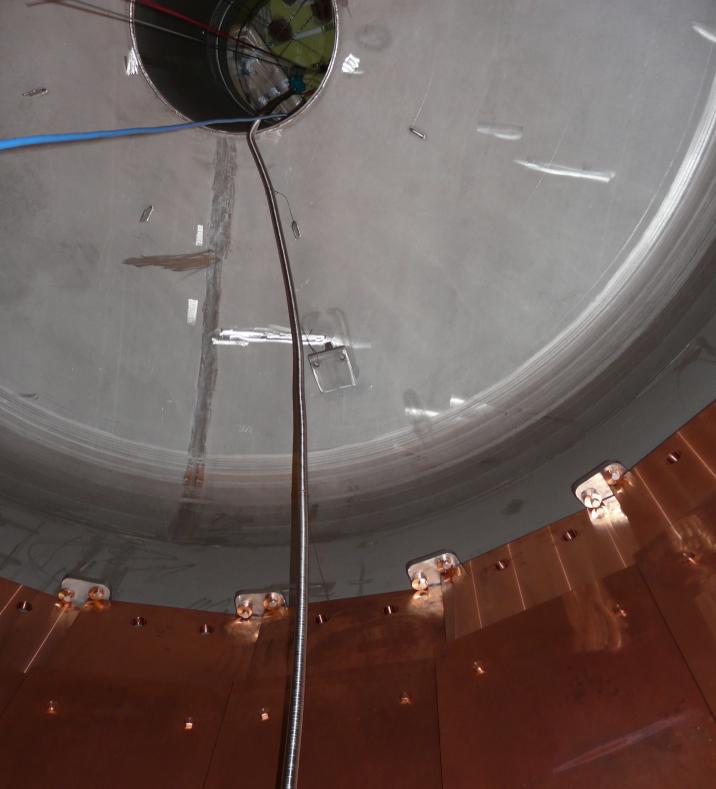
situation before cleaning



after cleaning



sticky dust on top head pen writing + sticky dust/oxide on copper loose fibers on bottom head



flexible tube with internal Pt100

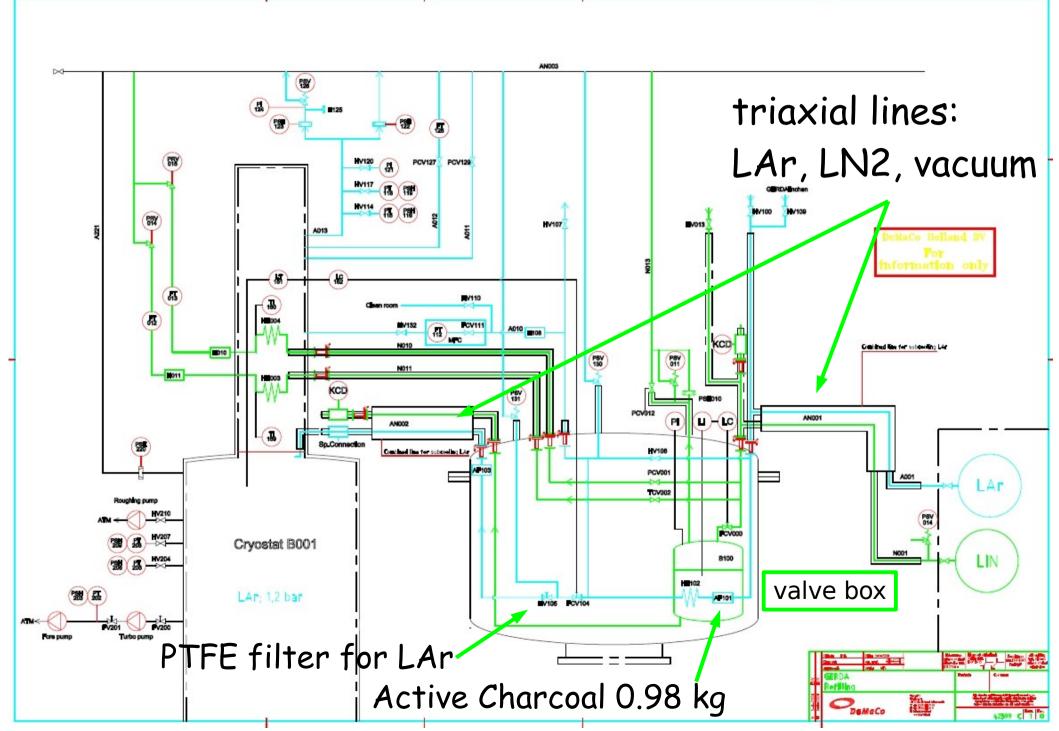
used for - LAr temperature - fill level - LAr drainage

The exhausted cleaning crew



missing on the picture: Stefano Gazzana & Matthias Junker

Final PI&D by DeMaCo



PTFE filter for LAr: 50 nm pore size & 2 filters in series



Fluorogard[®] AT and ATX Cartridge Filters

Broad chemical compatibility in medium to high flow microelectronics process chemical applications



Delivering Quality Performance

Fluorogard AT and ATX cartridge filters are fully constructed of fluoropolymer materials and are designed to efficiently remove particles from a broad range of acids, bases, solvents and other microelectronic process chemicals. These cartridges are recommended for medium to high flow applications. ATX cartridges are also ideal for high viscosity filtration applications.

Cost Effective Filtration

The Teflon[®] PTFE membrane and PFA pleated supports are compatible with a wide range of microelectronics process chemicals. These inert materials provide longer filter lifetime, thereby resulting in cost savings. The pleated filter design is recommended for systems where back pressure may occur.

Superior Filtration Efficiency

Increased filtration area is provided to minimize pressure drop and enhance particle removal performance. A variety of retention ratings are available to suit specific application needs.

Clean, Durable Construction

The Teflon fluoropolymer materials and thermallybonded construction minimizes extractables. Additionally, no surfactants or adhesives are used, eliminating potentially harmful contaminants that can adversely impact device yield.

Superior Manufacturing

Fluorogard AT and ATX filters are manufactured in a world-class, ISO Quality Systems Standard facility. To ensure reliability, each cartridge is tested for integrity.

— Product Features

Highly retentive hydrophobic PTFE membrane and PFA supports

Large membrane area

Cartridges shown with

optional Chemlock® Key.

All-fluoropolymer materials of construction

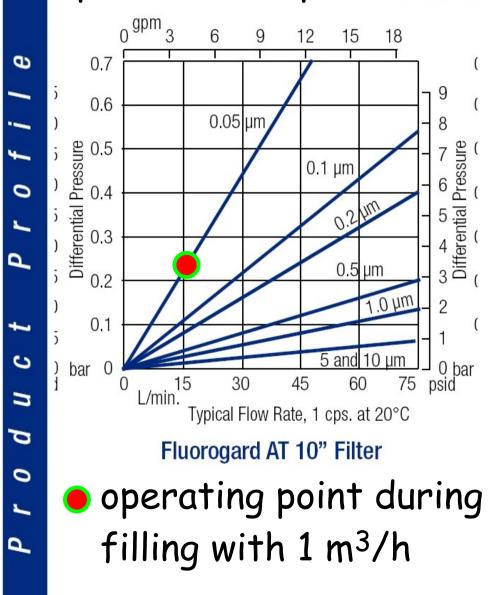
Product Benefits

Rugged materials provide superior resistance in strong chemical processing, pulsing, and high pressure applications. PFA supports provide excellent downstream cleanliness.

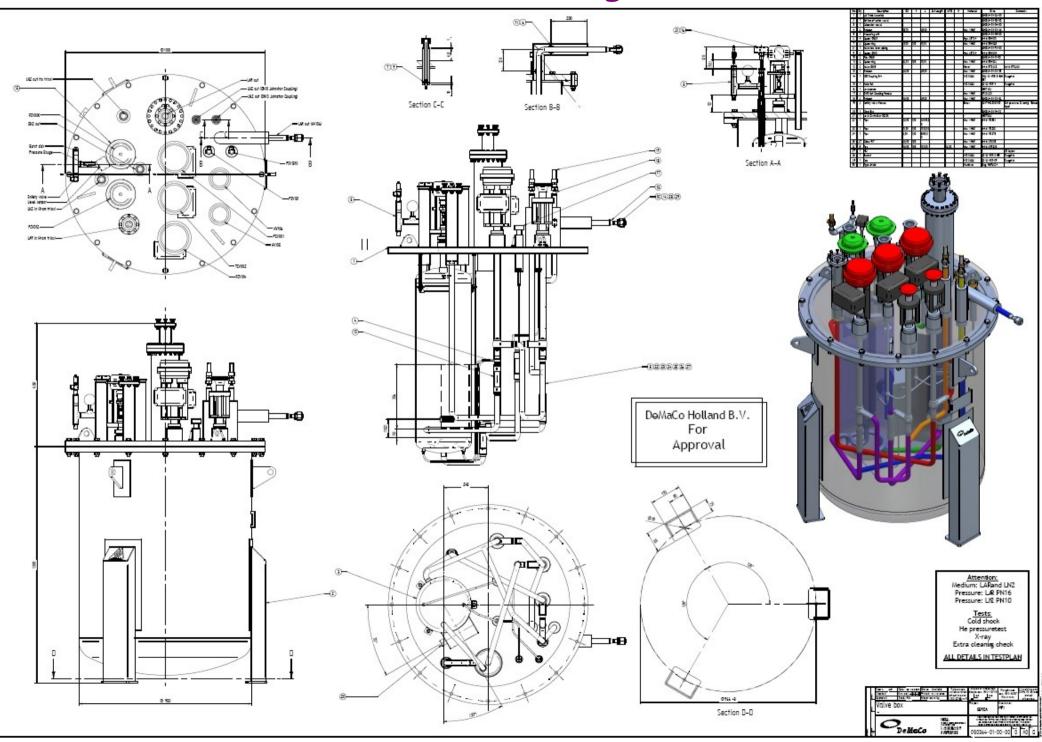
Minimizes pressure drop, provides high flow, and delivers longer filter lifetime.

Provides a broad range of chemical compatibility. Suitable for a variety of chemicals and solvents.

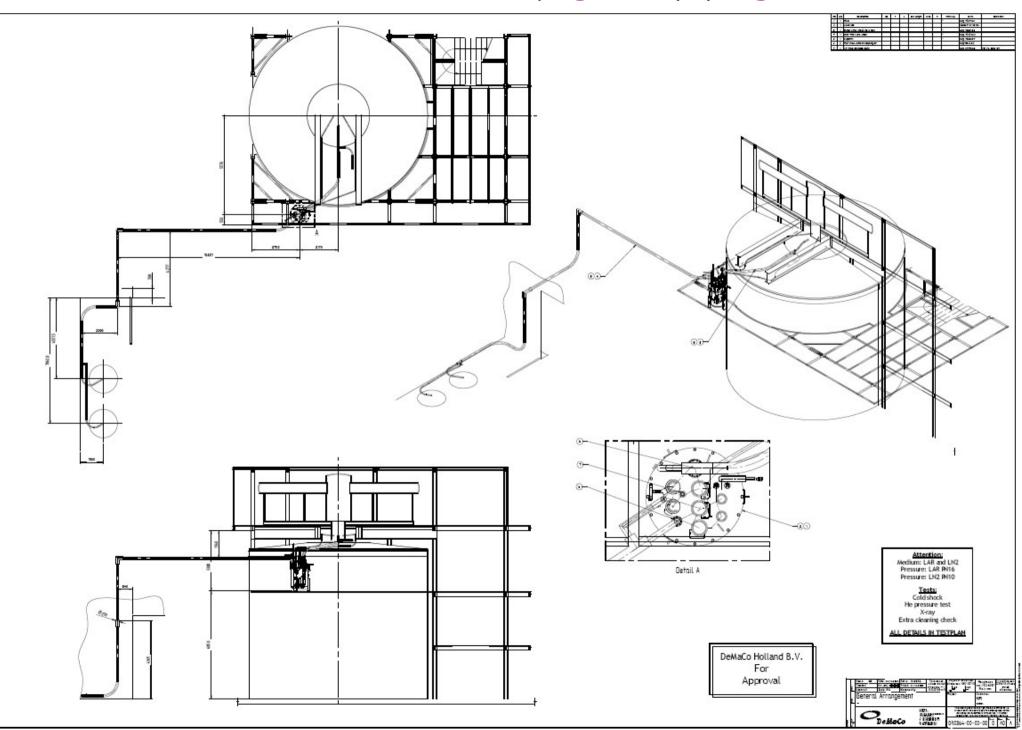
pressure drop for water



valve box design



Isometric view of cryogenic piping



Status & Schedule

contract signed with DeMaCo beginning of Oct 08 scheduled assembly at LNGS in Jan 09 possible delays:

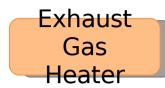
- flat top for valve box
- cryogenic values from Flowserve (resposibility of MPI)
 expected delivery first batch shifted 18 Oct --> 11 Nov

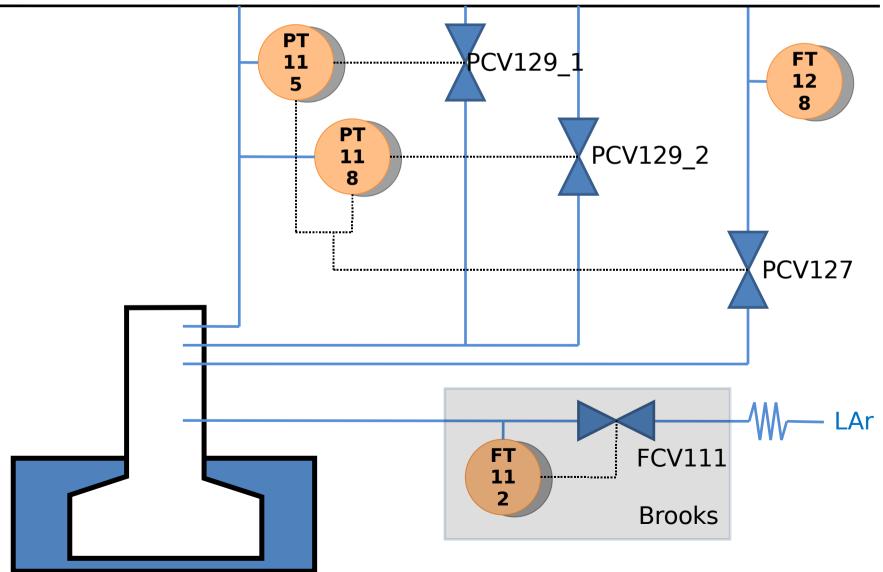
PLC

Simatic S7 and other components delivered PLC cabinet in production, ready in a few days programming has started (especially WEB interface, FTP server + HART comm. to field devices) have to finalize specification!! (e.g. emptying water tank)

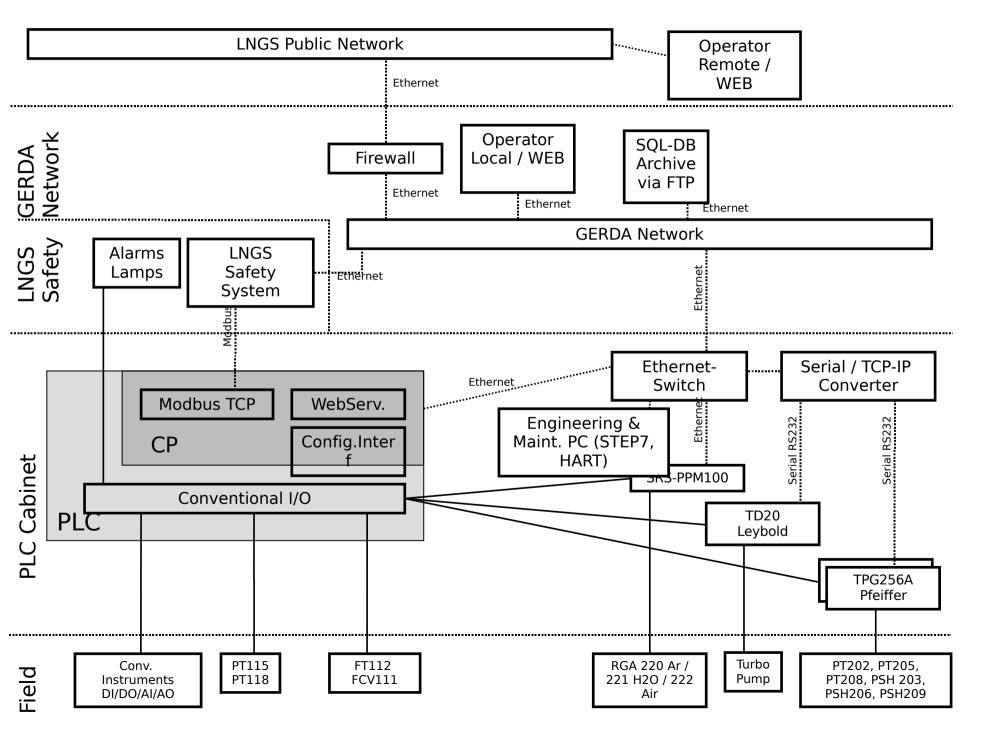
Example of WEB page from PLC

Pressure Control





PLC communication diagram



Summary

- mechanical cleaning of accessible surfaces finished
- waiting for emanation result bets? KTK: below 14 mBq BS: 25 mBq
- if emanation is too high: remove copper
- cryogenic infrastructure under production main installation in Jan 09
- still a lot of items on the to-do-list
 (explosion proof door, LN2 + LAr storage, holes, non-cryogenic pipes, vacuum, mounting, ...)
- PLC ready in time

ready for LAr filling in March 09 after cleanroom constr.